

[SS 1] ..fi epodoc

 Database: EPODOC

[EPODOC: SS 1] Controlled and pressure and drilling

Results in EPODOC 1.960

[SS 2] ss1 and flow and measurement

Results in EPODOC 3

[SS 3] ..li



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PN - [JP2013002809](#) A 20130107

PR - JP20110130472 20110610

AP - JP20110130472 20110610

DT - I

FI - A61L101/02; A61L2/20; A61L2/20&A; A61L2/20&G; A61L2/24; G01N21/59&Z

FT - 2G059/AA01; 2G059/BB01; 2G059/CC05; 2G059/DD12; 2G059/EE01; 2G059/GG02;
2G059/HH02; 4C058/AA12; 4C058/AA23; 4C058/AA24; 4C058/AA25; 4C058/BB07;
4C058/DD01; 4C058/EE26; 4C058/JJ16; 4C058/JJ27

PA - SAIAN CORP

TI - GAS SENSOR DEVICE AND STERILIZATION SYSTEM EMPLOYING THE SAME

AB - PROBLEM TO BE SOLVED: To stably measure a low-concentration area at high speed and with high accuracy in a gas sensor.SOLUTION: In NOgas concentration sensors S1, S2, a first **flow** passage H0 and a plurality of second **flow** passages H1 to H4 are provided which are disposed in parallel with each other as gas **flow** passages. In the first **flow** passage H0, a high-concentration gas sensor SP comprised of a photosensor is provided and in the second **flow** passages H1 to H4, low-concentration gas sensors **SS1** to SS4 comprised of semiconductors are provided, respectively. At an upstream side of the low-concentration gas sensors **SS1** to SS4, solenoid valves VS1 to VS4 are provided. After a **measurement** of the sensor SP is reduced sufficiently in a photosensor circuit C2, a valve control circuit C1 of a control device C alternatively "opens" the solenoid valves VS1 to VS4 and allows a semiconductor sensor circuit C3 to perform **measurement** . Therefore, the high-sensitivity sensors **SS1** to SS4 are not exposed uselessly under Nogas in the non-**measurement** state to prevent deterioration or breakdown, and can be used stably over a wide range from a high concentration area to a low concentration area.

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PN - [JPH0720279](#) A 19950124

PR - JP19930165762 19930705

AP - JP19930165762 19930705

DT - I

CCA - [Y02E30/40](#)

FI - G05B23/02&302R; G21D3/04&L

FT - 3C223/AA02; 3C223/AA03; 3C223/AA17; 3C223/BA03; 3C223/CC02; 3C223/DD02; 3C223/DD03; 3C223/EB01; 3C223/EB02; 3C223/FF02; 3C223/FF06; 3C223/FF32; 3C223/FF35; 3C223/FF43; 3C223/GG01; 3C223/HH08; 3C223/HH22; 5H223/AA02; 5H223/AA03; 5H223/DD03; 5H223/EE05; 5H223/EE06; 5H223/EE29

PA - MITSUBISHI HEAVY IND LTD

TI - ABNORMALITY DIAGNOSING SYSTEM FOR PLANT MACHINE

AB - PURPOSE:To make highly reliable operation possible while alleviating the burden on the plant operator by allowing quick and accurate diagnosis of abnormality in the piping of condensation system without relying on the knowledge or experience of plant operator. CONSTITUTION:An abnormality diagnostic system 50 for condensation system piping receives a hot well water level **measurement** SS1 from a hot well water gauge 24, an opening signal for a hot well water level control valve 22, a make-up water **flow** rate **measurement** SS2 from a make-up water flowmeter 34, a supply water **flow** rate **measurement** SS3 from a supply water flowmeter 35, a drain **flow** rate **measurement** SS4 from a drain flowmeter 32, open/close control data of a spillover valve 27 and the hot well water level control valve 22, water level data of low pressure water supply heater group, and open/close control data of a low pressure supply water heater water level control valve. The diagnostic system 50 monitors the data, estimates the probability of breakage in the piping of condensation system based on these signals and data and issues an alarm in case of breakage.

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PN - [EP0866319](#) A1 19980923

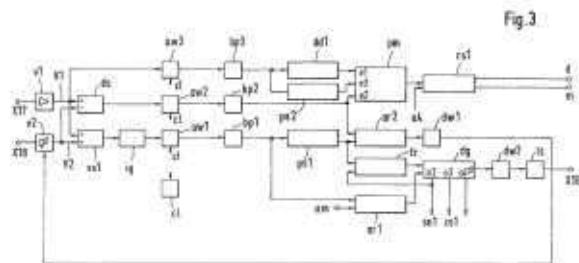
PNFP - EP0866319 B1 19991124

PR - EP19980810174
19980302; EP19970810169
19970321

AP - EP19980810174 19980302

DT - *; Rep

CT - || STSE (A1)
[WO8802105](#) A1 19880324
[A] (RHEOMETRON AG [CH])
[A] 1
* page 5, line 17 - line 28 *
* page 8, line 15 - line 32 *
* page 11, line 6 - page 13,
line 23; figure 2 *;
[US4852409](#) A 19890801
[A] (HERZL PETER J [US])
[A] 1
* column 5, line 24 - line 45 *



* column 6, line 36 - line 46;
figure 3 *;
[EP0698783](#) A1 19960228
[DA] (FLOWTEC AG [CH])
[DA] 1
* page 4, line 44 - page 5,
line 47; figure . *;
[US4934196](#) A 19900619
[DA] (ROMANO PAUL [US])
[DA] 1
* column 16, line 10 -
column 26, line 42; figures 2-4 *;
[EP0702212](#) A2 19960320
[DA] (FUJI ELECTRIC CO LTD [JP])
[DA] 1
* page 8, line 25 - page 10,
line 25; figures 10,13 *;
[US5429002](#) A 19950704
[DA] (COLMAN GERALD A [US])
[DA] 1
* column 8, line 6 - line 49;
figure 12 *;
[DE19525253](#) A1 19960118
[A] (YOKOGAWA ELECTRIC CORP
[JP])
[A] 1,3
* figure 4 *

- CCI - [G01F1/8409](#) ; [G01F1/8413](#) ;
[G01F1/8431](#) ; [G01F1/849](#) ;
[G01F15/024](#)
- PA - (A1 B1)
FLOWTEC AG [CH]
- TI - (A1 B1)
Measuring and operating circuit
of a Coriolis-type mass **flow**
meter
- AB - (A1)
The circuit has two
electromagnetic vibration
sensors and a stimulator
mounted on a **measurement**
tube which resonates depending
on the fluid density.
A **measurement** stage, first
digital-to-analogue converter
and a stimulation stage are also
included. The **measurement**
stage contains amplifiers (v1,

v2), adders (ss1), integration stage (ig), analogue-to-digital converters (aw1-aw3), a clock oscillator (c1) and a digital signal processor. The stimulator stage contains a digital generator (dg), a digital frequency regulator (fr), a digital amplitude regulator (ar1) and a second digital-to-analogue converter (dw2).

[SS 3]